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IAP11 Rec'd PCT/PTO 03 AUG 2006

INFORMATION DISCLOSURE STATEMENT 37 C.F.R. § 1.97(b)		ATTORNEY DOCKET NO. 70020.0079USWO	
		U.S. APPLICATION SERIAL NO. To Be Assigned	CONFIRMATION NO. N/A
		BASED ON INTERNATIONAL APPLICATION NO. PCT/JP2005/009128	
		INTERNATIONAL FILING DATE May 19, 2005	
INVENTOR(S) Takashi MIYAMATSU, et al.	EXAMINER To Be Assigned	GROUP ART UNIT N/A	
TITLE OF APPLICATION LIQUID FOR IMMERSION EXPOSURE AND IMMERSION EXPOSURE METHOD			

Mailstop Amendment
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Dear Sir:

With regard to the above-identified application, the items of information listed on the enclosed Form 1449 are brought to the attention of the Examiner.

This statement should be considered because it is submitted within three months of the filing date of the above-identified application, which is not an application under 37 C.F.R. § 1.53(d). Accordingly, no fee is due for consideration of the items listed on the enclosed Form 1449.

A copy of any foreign patent document or 'Other Document' listed on the Form 1449 is enclosed, in accordance with 37 C.F.R. § 1.98(a)(2). Because this application was filed after June 30, 2003, copies of the U.S. Patents and U.S. patent publications listed on the enclosed Form 1449 are not provided.

No representation is made that a reference is "prior art" within the meaning of 35 U.S.C. §§ 102 and 103 and Applicants reserve the right, pursuant to 37 C.F.R. § 1.131 or otherwise, to establish that the reference(s) are not "prior art." Moreover, Applicants do

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Consideration of the items listed is respectfully requested. Pursuant to the provisions of M.P.E.P. 609, it is requested that the Examiner return a copy of the attached Form 1449, marked as being considered and initialed by the Examiner, to the undersigned with the next official communication.

Please charge any additional fees or credit any overpayment to Deposit Account No. 13-2725.

Respectfully submitted,
MERCHANT & GOULD, P.C.


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August 3, 2006

Date

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INFORMATION DISCLOSURE
STATEMENT (PTO 1449)

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TITLE OF APPLICATION LIQUID FOR IMMERSION EXPOSURE AND IMMERSION EXPOSURE METHOD		

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
A	5,817,256	10/06/1998	WEIPPERT				
B	US 2002/0006675 A1	01/17/2002	SHIGARAKI				
C	US 2004/0242825 A1	12/02/2004	SHISHIDO ET AL.				

FOREIGN PATENT DOCUMENTS						
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
D	JP 11-176727	07/02/1999	JAPAN			Abstract
E	JP 10-303114	11/13/1998	JAPAN			Abstract
F	JP 2003-160515	06/03/2003	JAPAN			Abstract
G	JP 2001-181217	07/03/2001	JAPAN			Abstract
H	JP 60-209536	10/22/1985	JAPAN			Abstract
I	JP 2004-123762	04/22/2004	JAPAN			Abstract
J	JP 2002-255866	09/11/2002	JAPAN			Abstract
K	JP 06-12452	02/16/1994	JAPAN			X
L	JP 09-241214	09/16/1997	JAPAN			Abstract
M	JP 07-220990	08/18/1995	JAPAN			Abstract
N	JP 2001-326162	11/22/2001	JAPAN			Abstract
O	WO99/49504	09/30/1999	WIPO			Abstract
P	AU 2747999	10/18/1999	AUSTRALIA			Abstract
Q	WO03/016365	02/27/2003	WIPO			Abstract
R	WO01/032739	05/10/2001	WIPO			Abstract
S	JP 62-094813	05/01/1987	JAPAN			Abstract

EXAMINER	DATE CONSIDERED

EXAMINER: Initial if the reference is considered, whether or not the citation is in conformance with MPEP 609. Draw a line through the citation if it is not in conformance and it is not considered. Include a copy of this form with the next communication to the Applicant.

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		BASED ON INTERNATIONAL APPLICATION NO. PCT/JP2005/009128	
INVENTOR(S) Takashi MIYAMATSU, et al.		EXAMINER (If known) Not Assigned	INTERNATIONAL FILING DATE May 19, 2005
			ART UNIT (If known) N/A

FOREIGN PATENT DOCUMENTS								
	T	JP 2001-068400	03/16/2001	JAPAN			Abstract	
	U	JP 11-233402	08/27/1999	JAPAN			Abstract	
	V	JP 2005-072230	03/17/2005	JAPAN			Abstract	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
	W Inside Memory, Nikkei Microdevice, p. 77-86 (April 2004).
	X Smith, et al., Approaching the numerical aperture of water-Immersion lithography at 193nm, Proc. SPIE, Vol. 5377, pp. 273-284 (2004).
	Y Sylvester-Hvid, et al., Refractive Indices of Molecules in Vapor and Liquid: Calculations on Benzene, J. Phys. Chem. A, Vol. 103, No. 42, pp. 8447-8457 (1999).
	Z Immersion Lithography Modeling 2003 year-End Report (International SEMATECH).
	AA The seminar text of special seminar on immersion exposure technology, pp. 14-33 (May 27, 2004).

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